



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor/Applicant:

Justin K. Brask et al.

Serial No.: 10/626,336

Filed: July 24, 2003

For: Forming a High Dielectric Constant
Film Using Metallic Precursor

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Art Unit: 2811

Examiner: Ori Nadav

Atty Docket: ITL.1022US
P16709

Assignee: Intel Corporation

Mail Stop **Amendment**
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REPLY TO PAPER NO. 072505

Sir:

In response to the office action mailed September 2, 2005, please amend the above-referenced patent application as follows:

Date of Deposit: November 17, 2005

I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as **first class mail** with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Cynthia L. Hayden
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